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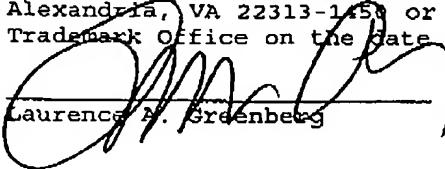
Practitioner's Docket No.: MUH-12818

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CERTIFICATION OF MAILING OR TRANSMISSION

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Laurence A. Greenberg

May 25, 2006
Date

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application No. : 10/675,049 Confirmation No.: 5871
Filing Date : September 30, 2003
Applicant : Ioannis Dotsikas
Title : Method and Furnace for the Vapor Phase Deposition of Components onto Semiconductor Substrates with a Variable Main Flow Direction of the Process Gas :
TC/AU : 2818
Examiner : Duang A. Le
Customer No. : 24131

SUPPLEMENTAL AMENDMENT

Mail Stop Fee Amendment
Hon. Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

S i r :

Supplemental to the amendment filed May 15, 2006, and responsive to the Office action dated February 16, 2006, kindly amend the above-identified application as follows:

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

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Remarks/Arguments begin on page 9 of this paper. 100.00 OP